CLAIM AMENDMENT

Please **CANCEL** claims 33-55 without a disclaimer or prejudice thereto.

Please **AMEND** claims 1 and 28, as follows.

Please **ADD** new claim 56, as follows.

1. (Currently Amended) An in-line system for manufacturing liquid crystal displays, comprising:

~~a spacer-dispersing unit for dispersing spacers on one of two substrates of a mother glass, the mother glass having at least one liquid crystal cell;~~

a sealant-applying unit for depositing sealant on one of ~~the~~ two substrates, either one of the two substrate having at least one liquid crystal cell ;

a liquid crystal depositing unit for depositing liquid crystal material on the substrate where the sealant is deposited; and

a substrate-attaching unit for receiving the two substrates from the sealant-applying unit or the liquid crystal depositing unit, then conjoining the substrates in a vacuum state.

2. (Original) The in-line system of claim 1, further comprising:

a first loading unit where one of the two substrates is loaded, and a second loading unit where one of the two substrates is loaded; and

a substrate-combination unit for providing the two substrates to the substrate-attaching unit.

3. (Original) The in-line system of claim 2, further comprising a sealant heat-treating unit for forming a reaction-prevention layer on a surface of the sealant such that a reaction between the sealant and the liquid crystal material is prevented.

4. (Original) The in-line system of claim 3, wherein the first loading unit, the spacer-dispersing unit, the sealant-applying unit, the liquid crystal depositing unit, the substrate-combination unit, and the substrate-attaching unit are combined in this sequence through first, second, third, fourth and fifth in-line conveying units, which transport the substrates to these elements in predetermined in-line process time units.

5. (Original) The in-line system of claim 4, wherein the second loading unit is connected to the substrate-combination unit through a sixth in-line conveying unit.

6. (Original) The in-line system of claim 3, wherein the first loading unit, the sealant-applying unit, the liquid crystal depositing unit, the substrate-combination unit, and the substrate-attaching unit are combined in this sequence through first, second, third and fourth in-line conveying units, which transport the substrates to these elements in predetermined in-line process time units.

7. (Original) The in-line system of claim 6, wherein the second loading unit, the spacer-dispersing unit and the substrate-combination unit are connected in sequence through fifth and sixth in-line conveying units.

8. (Original) The in-line system of claim 1, wherein the substrate-attaching unit includes two or more vacuum chambers for conjoining the substrates in a vacuum state in a predetermined in-line process time unit.

9. (Original) The in-line system of claim 8, wherein the vacuum chambers are connected in series such that the substrates are provided to a subsequent process in a predetermined vacuum state, each vacuum chamber holding the substrates for a predetermined in-line process time.

10. (Original) The in-line system of claim 8, wherein the vacuum chambers are connected in parallel such that the substrates are provided to a subsequent process in a predetermined vacuum state, each vacuum chamber holding the substrates for a predetermined in-line process time.

11. (Original) The in-line system of claim 1, wherein the substrate-attaching unit includes a first compression plate and a second compression plate for supporting the two substrates and applying a predetermined force toward each other such that the two substrates are pressed together; and an exposure unit for hardening the sealant.

12. (Original) The in-line system of claim 1, wherein the substrate-attaching unit includes a first compression plate and a second compression plate for supporting the two substrates and applying a predetermined force toward each other such that the substrates are pressed together, the first compression plate and the second compression plate having at least

one vacuum hole for exhausting air from between the compression plates; a support tube provided between the first compression plate and the second compression plate for sealing a space therebetween, the support tube having an inner space from which air can be exhausted such that an interval between the compression plates can be adjusted; and an exposure unit for hardening the sealant.

13. (Original) The in-line system of claim 12, wherein the substrate-attaching unit has a plurality of the vacuum holes at predetermined locations, and air is exhausted from the vacuum holes in a predetermined sequence.

14. (Original) The in-line system of claim 13, wherein the vacuum holes are formed at corners or center portions of each side of the first compression plate and the second compression plate.

15. (Original) The in-line system of claim 13, wherein the vacuum holes are shaped as slits of a predetermined length.

16. (Original) The in-line system of claim 1, wherein the liquid crystal depositing unit includes a liquid crystal depositer that is a syringe-type device such that the liquid crystal material can be deposited at specific predetermined locations in the liquid crystal cell.

17. (Original) The in-line system of claim 1, wherein the liquid crystal depositing unit is a spray-type device such that the liquid crystal material can be deposited over an entire surface of the liquid crystal cell.

18. (Original) The in-line system of claim 1, wherein the sealant-applying unit deposits the sealant in a closed loop, that is, without a liquid crystal injection hole.

19. (Original) The in-line system of claim 1, wherein the sealant is a material that is hardened by infrared rays.

20. (Original) The in-line system of claim 1, wherein the sealant includes one or more buffer regions that have a predetermined area to allow for flow of excess liquid crystal material.

21. (Original) A liquid crystal depositing unit for manufacturing a liquid crystal display, comprising:

a depositer for depositing liquid crystal material in liquid crystal cell of one of two substrates of a mother glass.

22. (Original) The liquid crystal depositer of claim 21, wherein said depositer is a syringe-type device such that the liquid crystal material can be deposited at specific predetermined locations in the liquid crystal cell.

23. (Original) The liquid crystal depositer of claim 21, wherein the depositer is a spray-type device having a plurality of nozzles such that the liquid crystal material can be deposited over an entire surface of the liquid crystal cell.

24. (Original) A substrate-attaching unit for manufacturing a liquid crystal display, the substrate-attaching unit attaching, in a vacuum state, two substrates of a mother glass having at least one liquid crystal cell region.

25. (Original) The substrate-attaching unit of claim 24, wherein the substrate-attaching unit includes a first compression plate and a second compression plate for supporting the two substrates and applying a predetermined force toward each other such that the substrates are pressed together; and an exposure unit for hardening a sealant between the substrates.

26. (Original) The substrate-attaching unit of claim 24, further comprising:

a first compression plate and a second compression plate for supporting the two substrates and applying a predetermined force toward each other such that the substrates are pressed together, a first compression plate and the second compression plate having at least one vacuum hole for exhausting air from between the compression plates;

a support tube provided between the compression plates for sealing a space therebetween, the support tube having an inner space from which air can be exhausted such that an interval between the compression plates can be adjusted; and

an exposure unit for hardening the sealant.

27. (Original) The substrate-attaching unit of claim 26, wherein there are provided a plurality of the vacuum holes at predetermined locations, and air is exhausted from the vacuum holes in a predetermined sequence.

28. (Currently Amended) The substrate-attaching unit of claim 27, wherein the vacuum holes are formed at corners or center portions of each side of the first compression plate and ~~thesecond~~ the second compression plate.

29. (Original) The substrate-attaching unit of claim 28, wherein the vacuum holes are shaped as slits of a predetermined length.

30. (Original) The substrate-attaching unit of claim 24, wherein the substrate-attaching unit includes two or more vacuum chambers for conjoining the substrates in a vacuum state in a predetermined in-line process time unit.

31. (Original) The substrate-attaching unit of claim 30, wherein the vacuum chambers are connected in series such that the substrates are provided to a subsequent process in a predetermined vacuum state, each vacuum chamber holding the substrates for a predetermined in-line process time.

32. (Original) The in-line system of claim 30, wherein the vacuum chambers are connected in parallel such that the substrates are provided to a subsequent process in a

predetermined vacuum state, each vacuum chamber holding the substrates for a predetermined in-line process time.

33-55. (Cancelled)

56. (New) The in-line system of claim 1, further comprising a spacer-dispersing unit for dispersing spacers on either one of two substrates.